

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Young-Soo Kim

Serial No.: 10/615,038

Filed: July 8, 2003

For: ATOMIC LAYER
DEPOSITION OF TITANIUM
NITRIDE USING BATCH TYPE
CHAMBER AND METHOD FOR
FABRICATING CAPACITOR BY
USING THE SAME

Group Art Unit: 2891

Examiner: Bradley Smith

I hereby certify that this paper (or fee) is being deposited with the United States Postal Service, first class postage prepaid, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

October 12, 2005

James P. Zeller Reg. No. 28,491

AMENDMENT AFTER ALLOWANCE UNDER 37 C.F.R. § 1.312

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Please amend this application as follows:

the amendments to the specification section begins on page 2 of this paper;

the remarks section begins on page 3 of this paper.